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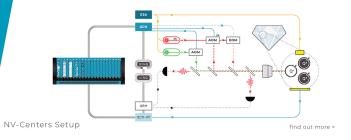
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Coherent heteroepitaxy of Bi₂Se₃ on GaAs (111)B

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We report the heteroepitaxy of single crystal thin films of Bi_2Se_3 on the (111)B surface of GaAs by molecular beam epitaxy. We find that Bi2Se3 grows highly c-axis oriented, with an atomically sharp interface with the GaAs substrate. By optimizing the growth of a very thin GaAs buffer layer before growing the Bi₂Se₃, we demonstrate the growth of thin films with atomically flat terraces over hundreds of nanometers. Initial time-resolved Kerr rotation measurements herald opportunities for probing coherent spin dynamics at the interface between a candidate topological insulator and a large class of GaAs-based heterostructures. © 2010 American Institute of Physics. [doi:10.1063/1.3532845]

The narrow band gap semiconductor Bi2Se3 has recently emerged as a promising basis for creating a state of matter known as a topological insulator (TI), wherein protected states can be produced at the surface of the material via the locking of spin and momentum by the constraints of time reversal symmetry.^{1–3} The prediction that it has the requisite electronic structure for forming these special conducting surface states spanning its bulk electronic energy gap has been confirmed by angle resolved photoemission spectroscopy.³⁻ With a bulk band gap (~ 0.3 eV) larger than other relevant materials, Bi₂Se₃ is one of the best candidate materials for engineering of the Fermi energy into the bulk band gap, so that transport can occur only through these surface states. However, this simple prescription has proved hard to realize because of an inherent tendency of the material to form Se vacancies or antisites that serve as donors,⁶ moving the Fermi energy far above the gap and making the contribution of the surface states to transport properties difficult to detect.

The growth of Bi₂Se₃ by molecular beam epitaxy (MBE) provides a potentially attractive solution for minimizing such defects by allowing for flexible control of growth conditions. To date, MBE growth of Bi₂Se₃ has been demonstrated on several substrates, including silicon, graphene, and SrTiO₃, albeit without complete removal of midgap states.⁸⁻¹² For silicon, the MBE growth of single crystal Bi₂Se₃ requires the introduction of an intermediate layer (e.g., a monolayer of Bi or amorphous layers) that improves the film quality by effectively decoupling it from the substrate, while graphene is conductive, complicating transport measurements of the surface states. In this letter, we report the heteroepitaxy of Bi₂Se₃ thin films upon another technologically important substrate material, GaAs. Notably, we show that the epitaxial growth is coherent with the substrate, thus opening routes for exploring the coupling of spin polarized TI states with electronic states in a wide variety of advanced semiconductor heterostructures, including magnetically doped III-V and II-VI semiconductors.

We carried out MBE growth of Bi2Se3 thin films on epiready semi-insulating GaAs (111)B substrates using thermal evaporation of high purity (5N) elemental Bi and Se from conventional Knudsen cells. After thermal desorption of the native oxide on the substrate under an arsenic flux, we first deposited a very thin GaAs buffer layer (~18 monolayers), yielding a very flat GaAs surface without the pitting of the surface that occurs with desorption of the oxide or the three dimensional hillocks that form with thicker buffers.¹ Bi₂Se₃ was then grown at a substrate thermocouple temperature of 400 °C (corresponding to an estimated actual substrate temperature of ~320 °C) and a Se:Bi beam equivalent pressure ratio ranging from $\sim 10:1$ to $\sim 30:1$.

Bi₂Se₃ has a tetradymite trigonal crystal structure with a rhombohedral unit cell that can be viewed as consisting of three sets of groupings of Se-Bi-Se-Bi-Se planes commonly referred to as quintuple layers (QLs). Each Se or Bi plane within the QL is a two dimensional hexagonal lattice. This matches the hexagon structure of the GaAs (111) surface with a lattice mismatch of 3.55%. We have grown Bi₂Se₃ films ranging in thickness from ~ 30 nm down to a few QLs $(\sim 3 \text{ nm})$ with a typical growth rate of $\sim 0.85 \text{ QL/min}$. Reflection high energy electron diffraction (RHEED) measurements during growth of Bi2Se3 indicate an unreconstructed surface [Fig. 1(a)]. We have also observed RHEED oscillations of the specular spot (data not shown), with each oscillation corresponding to the growth of a QL, indicating that the Bi₂Se₃ thin films grow layer-by- layer.^{9,11}

The morphology of the films was studied ex situ by atomic force microscopy (AFM). For some films, like the 25 nm thick film shown in Fig. 1(b), we grew a second buffer of ZnSe, only a few monolayers thick, by atomic layer epitaxy. While we were unable to directly confirm the presence of ZnSe in these samples by x-ray diffraction (XRD) or Raman spectroscopy, they did tend to result in very flat Bi₂Se₃ surfaces with rms roughness of $\sim 0.5\,$ nm. Samples without the ZnSe buffer were slightly rougher with an average rms roughness of a few nanometers. Very thin films of 2-3 QLs appear to exhibit islandlike growth, similar to observations made for growth of Bi₂Se₃ on graphene.¹¹ XRD measurements show reflections only from the (003) family of planes of the film, indicating that the films are highly c-axis oriented along the growth direction (Fig. 2). The rocking curve yielded a full width half maximum of 0.1°, significantly bet-

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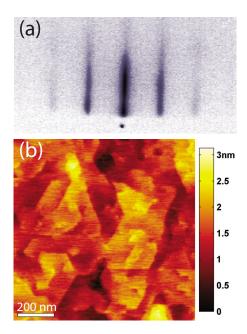


FIG. 1. (Color online) (a) Streaky unreconstructed RHEED diffraction patterns such as this were usually observed along principal crystalline directions during and after the film growth. (b) AFM image of the surface of a Bi_2Se_3 film. Large terraces hundreds of nanometers across can be seen whose ~ 1 nm step heights are consistent with single QLs. The rms roughness of the film is ~ 0.5 nm.

ter than those reported for growth on vicinal Si substrates with an amorphous layer.⁹ While including a ZnSe buffer resulted in a flatter film, it also resulted in a wider rocking curve.

To confirm the epitaxial growth of the Bi_2Se_3 thin film, we have carried out high-resolution transmission electron microscopy (HRTEM) on one of the samples grown directly on the thin GaAs buffer. Figure 3(a) shows a typical HRTEM image at the interface of Bi_2Se_3 and GaAs. The lattice fringes of the phase contrast images show a good registry between the film and substrate without any amorphous growth or secondary phases occurring at the interface. The inset shows a selected area diffraction (SAD) pattern from

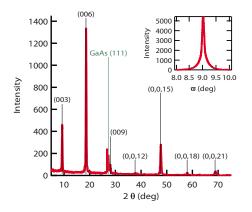


FIG. 2. (Color online) X-ray diffraction of a ~ 25 nm thick Bi₂Se₃ film. The (003) family of reflections shows that the films are highly c-axis oriented. Bi₂Se₃ peaks are labeled from Ref. 19. Inset shows the rocking curve of the (006) reflection giving a full width at half maximum of 0.1°.

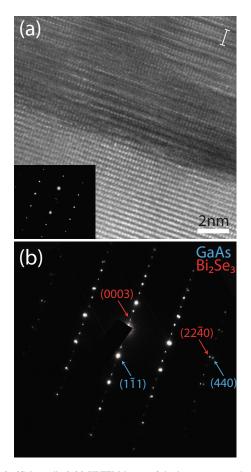


FIG. 3. (Color online) (a) HRTEM image of the heterostructure showing epitaxial growth of Bi_2Se_3 on the GaAs substrate without the formation of an amorphous layer at the interface. The distance (0.98 nm) between QLs is shown at the top right. Inset shows the diffraction pattern of the substrate. (b) Diffraction from the whole area in (a) showing both the GaAs and Bi_2Se_3 patterns. The c-axis Bi_2Se_3 film grows in registry with the hexagonal GaAs (111)B surface. The separation of the high index spots indicates that the film is relaxed in-plane.

just the GaAs substrate. Figure 3(b) shows the SAD pattern from the whole region spanning the interface. Besides the pattern due to GaAs (indices (110) and 440), the new spots [indices (0003) and (2240)] are consistent with a single crystal Bi₂Se₃ film that has grown epitaxially on GaAs. The interplanar distance between Bi₂Se₃ (2240) and GaAs (440) is found to be 0.336 nm⁻¹ in reciprocal space yielding a lattice mismatch in the *ab* plane of 3.62%, consistent with the expected value of 3.55%, and indicating that the film is relaxed. Surprisingly, we do not find any evidence of twinning or dislocations in the transmission electron microscopy (TEM) study, despite the large lattice mismatch. Both the HRTEM images and the diffraction patterns from several different areas show that the Bi₂Se₃ thin films are generally high-quality single crystals with a low density of defects.

Electrical transport studies were carried out at 4.2 K using lithographically patterned and wet etched Hall bars (with dimensions of $650 \times 400 \ \mu m^2$) in perpendicular magnetic fields up to 4 T. Electrical and Hall conductivity measurements reveal that all the samples studied are n-doped

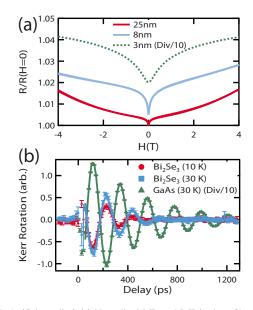


FIG. 4. (Color online) (a) Normalized MR at 4.2 K in three films with varying thicknesses (t) and carrier densities (n): t=25 nm, $n=1.83 \times 10^{19}$ cm⁻³ (lower solid curve); t=8 nm, $n=3.99 \times 10^{19}$ cm⁻³ (upper solid curve); and t=3 nm, $n=1.71 \times 10^{19}$ cm⁻³ (dashed curve). The normalized MR of the 3 nm film is divided by 10 and curves are offset for clarity. (b) Circles and squares show the TRKR measured with an in-plane magnetic field of 0.75 T at the GaAs/Bi₂Se₃ interface in the 8 nm film described in (a). Triangles show the TRKR (divided by 10) from the GaAs substrate alone. Pump and probe wavelength is 810 nm.

with carrier densities in the range $8.06 \times 10^{18} \le n \le 4 \times 10^{19}$ cm⁻³ and mobilities in the range ~100 to ~1000 cm² (V s)⁻¹, consistent with previous reports of MBE growth.⁹ Thus, we are still faced with unintentional background doping, presumably from a lack of stoichiometry and perhaps some contributions from unintentional Cd contamination from an earlier source in our MBE chamber. Magnetoresistance (MR) curves are shown in Fig. 4(a) for various film thicknesses. All show a positive MR cusp, consistent with weak antilocalization corrections to diffusive transport and typical of measurements of Bi₂Se₃ reported in the literature.^{14,15} A systematic analysis of the temperature, magnetic field, and sample thickness dependence of the MR will be reported elsewhere.

Finally, we discuss preliminary magneto-optical measurements that probe spin-dependent phenomena associated with the interface in these heterostructures. We used a wellestablished time-resolved Kerr rotation (TRKR) technique¹⁶ to demonstrate a possible method of probing spin polarization in a TI via coupling to spin states in a conventional semiconductor. Figure 4(b) shows TRKR curves for optically injected spins in the GaAs substrate precessing in an in-plane magnetic field. Data measured through an 8 nm layer of Bi₂Se₃ are shown at two temperatures, along with reference data from an area where the Bi₂Se₃ layer was wet-etched away. By fitting the TRKR to a damped sinusoid,¹⁶ we deduce the g-factor and the inhomogeneous spin lifetime (T_2^*) . While the g-factor of spins in GaAs (g=-0.44) is unchanged by the overgrowth of Bi₂Se₃, T_2^* is significantly shorter at the Bi₂Se₃ interface: at T=30 K, $T_2^*=160$ ps at the interface, compared with $T_2^*=450$ ps in the reference region.

In summary, we have demonstrated the coherent epitaxial growth of the candidate TI material Bi_2Se_3 on GaAs (111)B substrates. The ability to synthesize Bi_2Se_3 epitaxial films with high-quality heterointerfaces on GaAs and ZnSe opens the door to a host of interesting heterostructure applications, including TI-magnetic semiconductor interfaces, where magnetic monopoles or Majorana fermions at domain walls could be studied.^{17,18}

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